INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket number (Optional)	Application Number			
15689.49.2	10/673,656			
Applicant(s)				
Takehiro Nakamura et al.				
Filing Date	Group Art Unit			

2616

September 29, 2003

U.S. PATENT DOCUMENTS									
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIRATE		
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		U.S	S. PATENT APPL	ICATION PUBLICATIONS					
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS FILING DATE IF APPROPRIRATE			
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			FOREIGN PA	TENT DOCUMENTS				. <u>.</u>	
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Trans YES	lation NO	
	1	0 682 418 A2	05/12/1995	EPO	H0487	005	X	NO	
	2	CN1126930	7/17/1996	China	H04B7	005	X		
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EXAMINER		1		DATE CONSIDERED					
EXAMINER: In not considered.	nitial if cit Include co	ation considered, whether or not c ppy of this form with next commun	itation is in confor ication to applicar	mance with MPEP Section 60	9; Draw line th	rough citation if	not in confo	mance and	

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*Examiner Initial	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)					
	3	Chinese Office Action for Chinese Patent Application No.: 20031010330.1				
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EXAMINER		DATE CONSIDERED				
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